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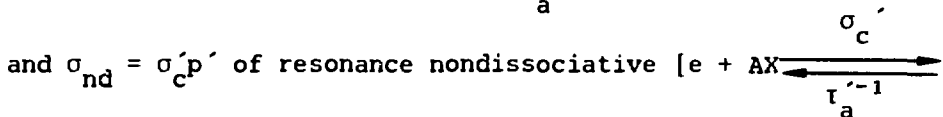
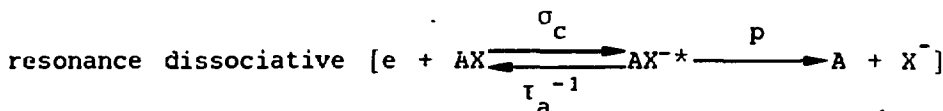
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EFFECTS OF TEMPERATURE ON DISSOCIATIVE AND
NONDISSOCIATIVE ELECTRON ATTACHMENT

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Results of recent studies on the effects of temperature, T, on the dissociative and nondissociative electron attachment to molecules are presented and discussed. These show the delicate and large effects of T on the cross section $\sigma_{da} = \sigma_c p$ of



For AX molecules where only dissociative attachment processes occur, the effect of T on σ_{da} is an increase in σ_{da} resulting from an increase in p principally because of a decrease in the separation time of A and X; the energy integrated σ_{da} increases with increasing average internal energy of AX. For AX molecules with pure nondissociative attachment, the effect of T is a decrease of σ_{nd} with increasing T resulting from a decrease in p' (i.e., an increase with T of $\tau'_a{}^{-1}$). For AX molecules with both dissociative and nondissociative processes the total rate constant (or cross section) increases or

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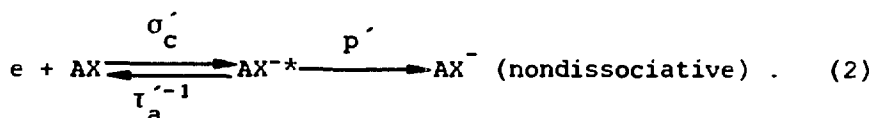
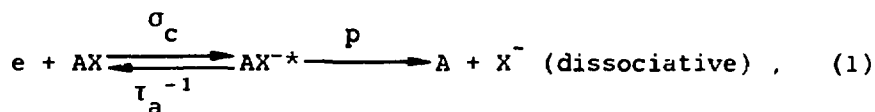
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decreases with T depending on the relative contribution of the dissociative and nondissociative processes. It appears that for both dissociative and nondissociative attachment the effect of T on σ_c or σ'_c is small except in those cases where electron capture by the hot molecule is accompanied by geometrical changes. Besides their intrinsic value, these results are of applied significance in many areas where the operating temperatures are higher than ambient and where the number density of electrons and negative ions crucially affects the performance of the device.

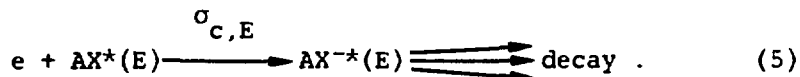
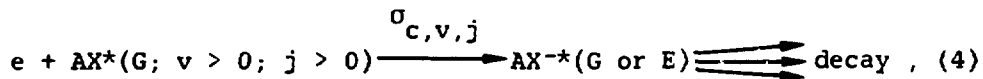
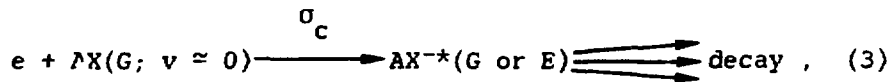
Introduction

Resonance electron attachment processes occur at low (≤ 20 eV) energies and are generally discussed within the formalism of the resonance scattering theory and the formation of transient negative ions. Thus, resonance dissociative and nondissociative electron attachment to a molecule AX is viewed as occurring in two steps: (a) capture of the electron by AX to form the transient anion AX^{-*} and (b) the subsequent decay or stabilization of AX^{-*} ; viz.,



In reactions (1) and (2), σ_c and σ'_c are the respective electron capture cross sections, p and p' are the probabilities for AX^{-*} to decay by stable fragment [Eq. (1)] or parent fragment [Eq. (2)] anion formation, and τ_a^{-1} and τ'_a^{-1} are the respective constants for AX^{-*} to decay by autodetachment. While many negative ion states (NISs) are usually involved in process (1), only one NIS (the lowest) is usually involved in process (2) [process (2) also requires that the electron affinity of AX is positive (>0 eV)]. In certain cases reactions (1) and (2) can proceed concomitantly and be in competition.

Processes (1) and (2) can be classified [1,2] according to the internal state of excitation of AX, viz.



In reaction (3), $AX(G = 0, v = 0)$ is a molecule in its ground electronic state G and predominantly in its lowest ($v = 0$) vibrational state of excitation, and $AX^{-*}(G \text{ or } E)$ is the transient anion formed in either the field of the ground (G) or the field of an excited (E) electronic state with a capture cross section σ_c . In reaction (4), $AX^*(G = 0, v > 0, j > 0)$ is a molecule in its ground electronic state, but in higher vibrational (v)/rotational (j) states, and $AX^{-*}(G \text{ or } E)$ is the respective transient anion formed with a cross section $\sigma_{c,v,j}$. In reaction (5) the target molecule $AX^*(E)$ is electronically excited, and the electron is captured in the field of an excited electronic state producing $AX^{-*}(E)$ with a cross section $\sigma_{c,E}$. Most studies to date concerned themselves with reaction (3). Swarm studies on reaction (5) are in progress at our laboratory. Electron attachment to "hot" molecules [reaction (4)] (the vibrationally/rotationally excited molecules can be formed by either laser excitation or by gas heating) have been reviewed [2].

In this paper we discuss reaction (4) with reference to published data and with reference to new results obtained at our laboratory on polyatomic halogenated compounds. Studies of the effects of temperature on the various electron attachment processes are of both intrinsic and of applied significance. With regard to the latter, in many applied areas the operating temperatures are higher than ambient and the performance of the various devices is crucially affected by the number density of electrons and negative ions (such is the case, for example, in diffuse discharge switches) and thus by T . Our discussion of resonance electron attachment to hot molecules will be separated into three parts: (a) electron attachment to molecules where only dissociative attachment processes occur, (b) electron attachment to molecules where only nondissociative electron attachment takes place, and (c) electron attachment to molecules where both dissociative and nondissociative electron attachment processes occur over an energy range.

Effects of Temperature on Electron Attachment to
Molecules Where Only Dissociative Attachment Occurs

Diatomic Molecules

The cross section, σ_{da} , for (1) can be expressed as

$$\sigma_{da} = \sigma_c p . \quad (6)$$

In Eq. (6) the capture cross section σ_c depends [2-4] on the autodetachment width Γ_a and the dissociation width Γ_d and varies inversely with the resonance energy ϵ_{max} ; the probability p is usually expressed as [2-4]

$$p = e^{-\tau_s/\tau_a} , \quad (7)$$

where τ_s is the average separation time of A and X^- , and τ_a is the average lifetime of AX^{*-} . As T increases, higher-lying vibrational levels of AX are populated for which the internuclear distances increase significantly (and hence the Franck-Condon region is broadened), and the magnitude of σ_{da} for molecules, AX^{*vibr} , in such excited nuclear motion states increases significantly; also, the threshold energy is lowered, and the Γ_d is increased (e.g., see Refs. 2, 5). Such an enhancement in σ_{da} , however, can be small in cases where the dissociative attachment process is exoergic and the potential energy curve for the transient negative ion AX^{*-} crosses that of the neutral molecule close to the equilibrium separation.

The increase in σ_{da} with T results from an increase in both σ_c [as higher vibrational levels of AX are populated, progressively lower energy electrons, for which σ_c is larger [2,6], are captured (also the Franck-Condon factors change)] and p . However, the increase in σ_c is usually small [except perhaps in those cases (e.g., N_2O [7]) where geometrical changes concomitant with electron capture occur] compared with that in p ; the latter dominates the T dependence of σ_{da} and results from a shortening of τ_s associated with the spatially more extended wavefunctions of AX^{*vibr} . Theoretical calculations [2,5,8,9] have shown that the effect of rotational excitation on σ_{da} is usually small and that the effect of vibrational excitation substantially accounts for the observed increases in σ_{da} with T.

The aforementioned conclusions are based on experimental and theoretical results on diatomic molecules (O_2 , H_2 , D_2 , HCl , DCl) [2,5,8-11]. Examples of these findings are shown in

Figs. 1 and 2. In Fig. 1 are plotted the calculated [8] values of σ_{da} close to the vertical onset for H^+/H_2 and D^+/D_2 for H_2 and D_2 in various vibrational levels v . In Fig. 2 the experimental (see figure caption) σ_{da} for Cl^- from HCl and DCl are shown for HCl/DCl in the $v = 0, 1,$ and 2 levels. The σ_{da} increases dramatically as the vibrational quantum number increases. For a given pair of isotopic molecules, the lower the vibrational energy $h\nu_x$ of a given mode x is, the larger is the effect of T on σ_{da} since at a fixed T higher levels v are populated for which τ_s is shorter (p larger). It should be realized, however, that unless T is very large or ϵ_{max} small, the increase of the measured σ_{da} with T is much smaller than indicated in Figs. 1 and 2 because σ_{da} is the Boltzmann-factor-weighted σ_{da} for all levels v_x , and only a small fraction (itself a function of the size x of $h\nu_x$) of molecules are in higher vibrational levels.

It has recently been pointed out [10] that the data in Figs. 1 and 2 show that the isotope effects observed [2,6] in the σ_{da} for H_2/D_2 and HCl/DCl (and for other molecules [2,6]) depend on T . As T increases, τ_s decreases and hence the isotope effects become less pronounced; for a given T , higher vibrational levels (for which p is larger) are populated in the heavier molecule ($h\nu_D < h\nu_H$) and thus the increase in σ_{da} with T is larger for the heavier than for the lighter analog (see insets in Figs. 1 and 2). Actually (see inset in Fig. 2), when HCl/DCl have vibrational energy >0.1 eV this increase in σ_{da} overtakes the opposite effect (decrease) introduced by the larger reduced mass of $D-Cl^-$ compared with $H-Cl^-$, so that the ratio $[\sigma_{da}(\epsilon_{max})]_{DCl} / [\sigma_{da}(\epsilon_{max})]_{HCl}$ which for HCl and DCl in the $v = 0$ level is equal to 0.71 (Ref. 12) becomes >1 .

The cross section data for the various v levels of H_2 and D_2 in Fig. 1 have been used [10] to determine the contributions to the total $\sigma_{da}(T)$ from the various vibrational levels at a number of T ; at each value of T the cross section for a particular vibrational level v (see Fig. 1) was multiplied by the fractional population of that level. The resultant cross sections $\sigma_{da}(v)$ are shown in Fig. 3 along with the total $\sigma_{da}(T)$ [the sum of $\sigma_{da}(v)$ over all contributing v levels]. Although these results are approximate (the cross sections in Fig. 1 for the various v are threshold values [8]), it is clear that as T increases the isotope effect decreases (see inset in Fig. 3).

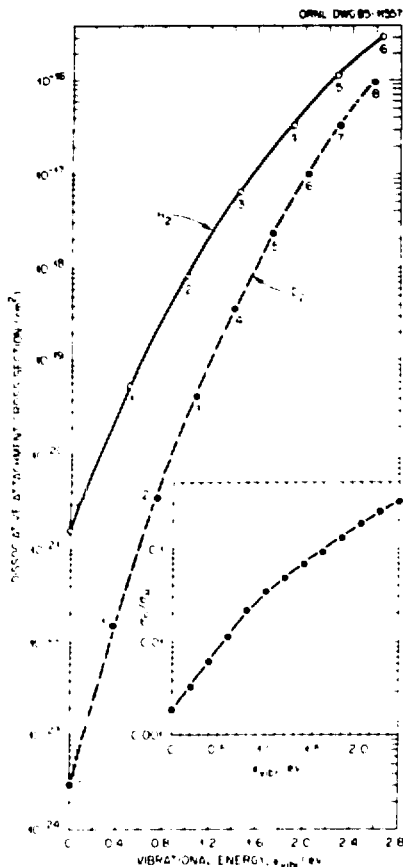


Figure 1. Calculated [8] σ_{da} for H^-/H_2 and D^-/D_2 with H_2/D_2 in various vibrational levels. The data are for energies close to the vertical onset. Inset: Ratio $\sigma_{D^-}/\sigma_{H^-}$ of the σ_{da} for D^-/D_2 and H^-/H_2 as a function of the neutral molecule's vibrational energy (from Ref. 10).

Similar calculations [10] for HCl and DCl are more limited since for these molecules only cross section data for the $v = 0, 1,$ and 2 levels are available (see Fig. 2) and the effect of rotational excitation of $\sigma_{da}(T)$ may not be insignificant [9,11] as was the case for H_2 and D_2 [8,14]. Nevertheless, the contributions to the total dissociative attachment cross section $\sigma_{da}(T)$ from the $v = 0, 1,$ and 2 vibrational levels in Fig. 4 show that the total $\sigma_{da}(T)$ of DCl exceeds that of HCl at $T > 650$ K (see inset in Fig. 4), while it is only 70% that of HCl at $T \approx 300$ K.

It is thus apparent [10] that the isotope effects observed in dissociative attachment depend on gas temperature; they are

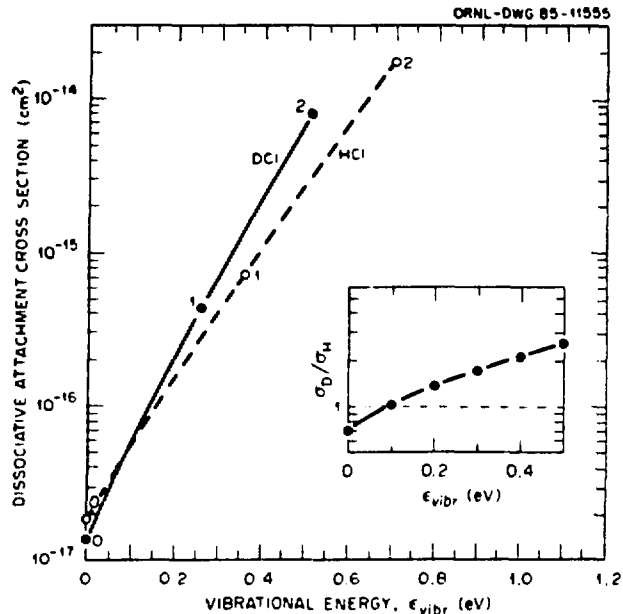


Figure 2. Experimental [11] σ_{da} for Cl^-/HCl and Cl^-/DCl for HCl and DCl in the $v = 0, 1,$ and 2 levels. These cross sections were obtained from the values reported in Ref. 11 for the ratios $\sigma_{da}(v = 1,2)/\sigma_{da}(v = 0)$ for HCl and DCl [$\sigma_{da}(v = 1)/\sigma_{da}(v = 0)$ and $\sigma_{da}(v = 2)/\sigma_{da}(v = 0)$ were reported [11] to be, respectively, 38 and 880 for HCl and 32 and 580 for DCl] and by normalizing the $\sigma_{da}(v = 0)$ relative cross section of Ref. 11 to the cross section measured [12] at $T \approx 300$ K (the peak value of σ_{da} for HCl and DCl is, respectively, equal to 1.95 and 1.4×10^{-17} cm^2 at ~ 0.8 eV [12]) (from Ref. 10).

the largest when the isotopic molecules are in their $v = 0$ levels. It is also apparent that while for diatomic molecules the ratio $\sigma_{da}(v > 0)/\sigma_{da}(v = 0)$ increases with increasing vibrational energy, for a given T the internal energy is a function of the magnitude of $h\nu_x$ and for polyatomic molecules also of the number of vibrational degrees of freedom N .

Polyatomic Molecules

Earlier work on the effect of T on σ_{da} of polyatomic molecules has been reviewed [2]. Recent work on freons, which are of interest as additives in multicomponent gas mixtures for use as gaseous dielectrics or in diffuse discharge switches, has been undertaken at our laboratory, and some of the results we obtained are presented and discussed in this and the following sections.

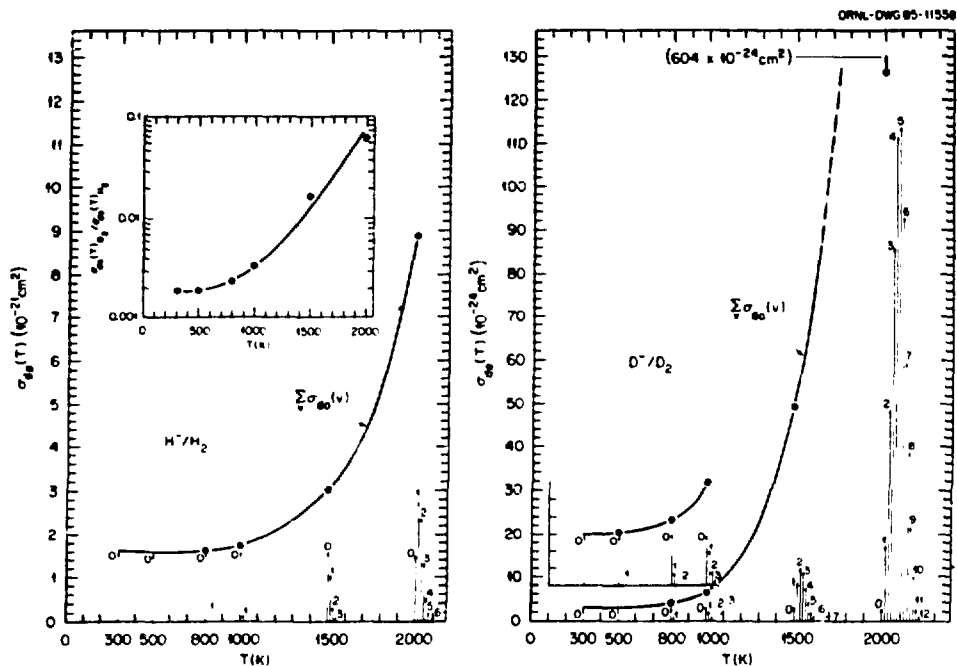


Figure 3. Dissociative attachment cross section $\sigma_{da}(T)$ for H/H_2 and D/D_2 at various T determined as described in the text. For each T the length of the vertical arrows designated by 0,1,2... gives the contribution $\sigma_{da}(v)$ to the total $\sigma_{da}(T) = \sum \sigma_{da}(v)$ of molecules, respectively, in the $v = 0,1,2...$ levels.

The energy, E_v , of the $v = 0,1,2...$ vibrational levels was determined using the formula $E_v = hc\omega(v + \frac{1}{2}) - hc\omega\chi_e(v + \frac{1}{2})^2$, where h is the Planck constant, c is the speed of light, and ω_e and $\omega_e\chi_e$ are the vibrational constants given in Ref. 13. As T increases, progressively larger contributions to $\sigma_{da}(T)$ come from molecules in higher vibrational quantum states. Inset: Ratio $\sigma_{da}(T)_{D_2} / \sigma_{da}(T)_{H_2}$ at various T (from Ref. 10).

CClF₃. In Fig. 5 are given the measured [15] total electron attachment rate constants $k_a(\langle \epsilon \rangle)$ as a function of the mean electron energy $\langle \epsilon \rangle$ for $300 \leq T \leq 700$ K. As T increases, k_a increases, especially at low $\langle \epsilon \rangle$. In Fig. 6 are shown the total electron attachment cross sections $\sigma_a(\epsilon)$ obtained [15] at each value of T from the respective $k_a(\langle \epsilon \rangle, T)$ in Fig. 5 via the swarm unfolding technique [16]. The peak at ~ 1.5 eV is especially sensitive to changes in T . The peak value of $\sigma_a(\epsilon)$ is increased by a factor of 3, and the energy position, ϵ_{max}^a , of the peak and the energy onset, A_0 , shift progressively to lower energy as T increases. Electron beam studies (inset,

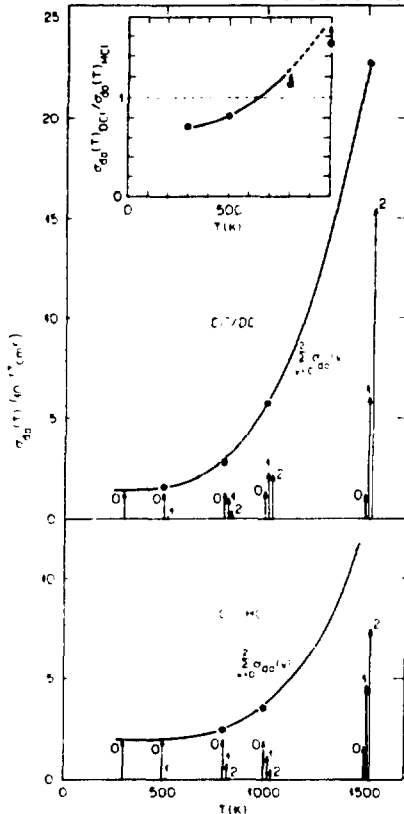


Figure 4. Dissociative attachment cross section $\sigma_{da}(T)$ for Cl_2/HCl and Cl_2/DCl at various T determined as described in the text. For each T the length of the vertical arrows designated by 0, 1, and 2 gives the contribution $\sigma_{da}(v)$ to the total $\sigma_{da}(T)$ of molecules, respectively, in the $v = 0, 1,$ and 2 vibrational levels (the energy of each vibrational level was determined as described in the caption of Fig. 3). The sum,

$\sum_{v=0}^2 \sigma_{da}(v)$, of the $\sigma_{da}(v)$ for the $v = 0, 1,$ and 2 levels is also given in the figure.

Since for $T > 1000$ K the contributions to $\sigma_{da}(T)$ of molecules in $v > 2$ is substantial, the values of $\sigma_{da}(T)$ [$\equiv \sum_{v=0}^2 \sigma_{da}(v)$] in the figure for 1000 and 1500 K are grossly underestimated.

As a consequence of this, the values of the ratio $[\sigma_{da}(T)]_{DCl} / [\sigma_{da}(T)]_{HCl}$ for 1000 and 1500 K (see inset) are lower than their true values (this is indicated in the inset by the data points †) (from Ref. 10).

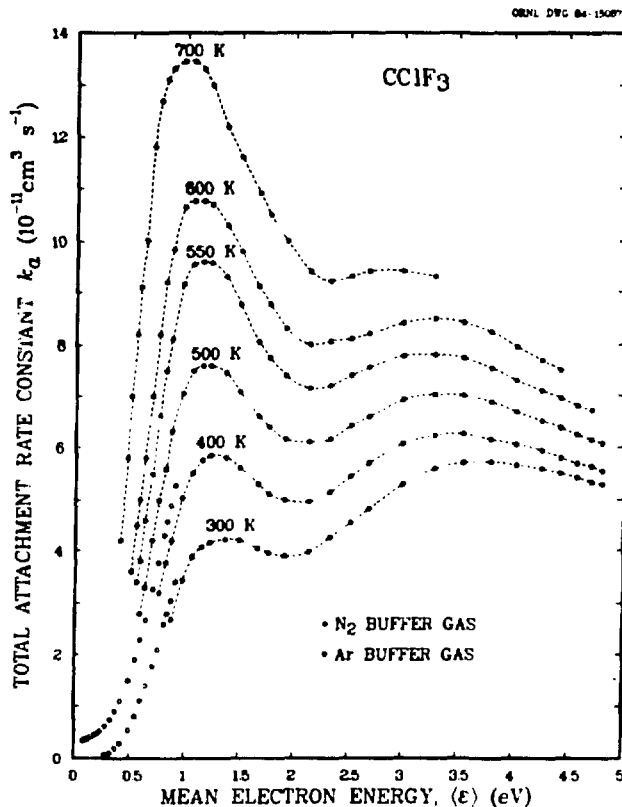


Figure 5. Total electron attachment cross section versus electron energy for CClF_3 measured [15] in the buffer gases N_2 or Ar at various temperatures; the $k_a(\langle \epsilon \rangle)$ were independent of gas number density.

Fig. 6) have shown [15] that at low gas pressures CClF_3 captures electrons exclusively via dissociative attachment and that the peaks at ~ 1.5 and ~ 4.7 eV are the former due to Cl^- and the latter due to Cl^- , F^- , CClF_2^- , and CClF^- ions.

C_2F_6 . In Fig. 7 the $k_a(\langle \epsilon \rangle, T)$ are given along with the relative abundance of the fragment negative ions observed (inset, Fig. 7) in a beam study [17]. No parent negative ions were observed in the low pressure beam study, and this is consistent with the absence of any pressure dependence of $k_a(\langle \epsilon \rangle, T)$ in the swarm study. In Fig. 8 are plotted the swarm unfolded cross sections which show a single peak due to F^- and CF_3^- (see inset of Fig. 7). The decrease in ϵ_{max} and AO and the increase in FWHM (full width at half maximum) of $\sigma_a(\epsilon)$ with T are shown in the inset of Fig. 8.

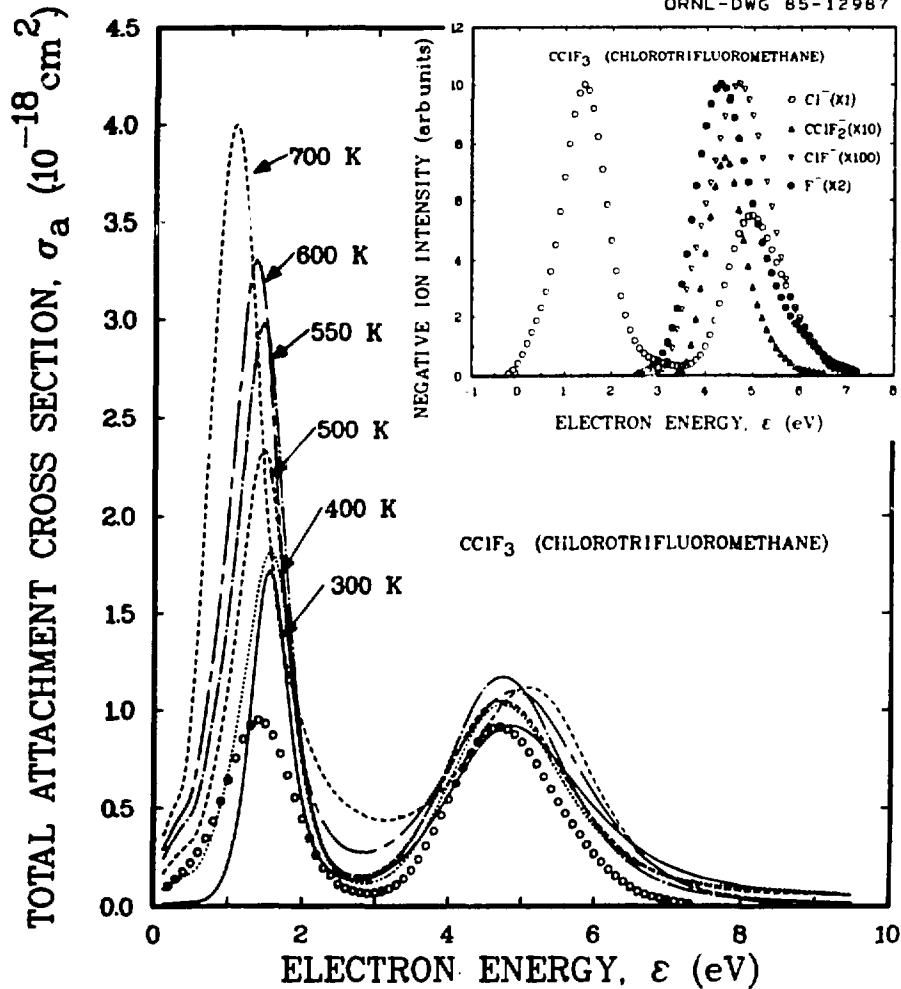


Figure 6. Total electron attachment cross section versus electron energy for CClF_3 unfolded from the $k_a(\langle \epsilon \rangle, T)$ data in Fig. 5 at various T . The curve designated by the open circles (o) is the electron beam total attachment cross section normalized to the high energy peak of the swarm unfolded cross section for 300 K. Inset: Relative intensity of the dissociative attachment negative ions produced by low energy electron impact on CClF_3 as a function of electron energy measured in a beam study (these spectra were corrected for the finite width of the electron pulse) [15].

In addition to the $k_a(\langle \epsilon \rangle, T)$ we measured in mixtures with Ar, we also measured the electron attachment, $\eta/N_a(E/N)$, and ionization, $\alpha/N_a(E/N)$, coefficients in pure C_2F_6 at 300 and

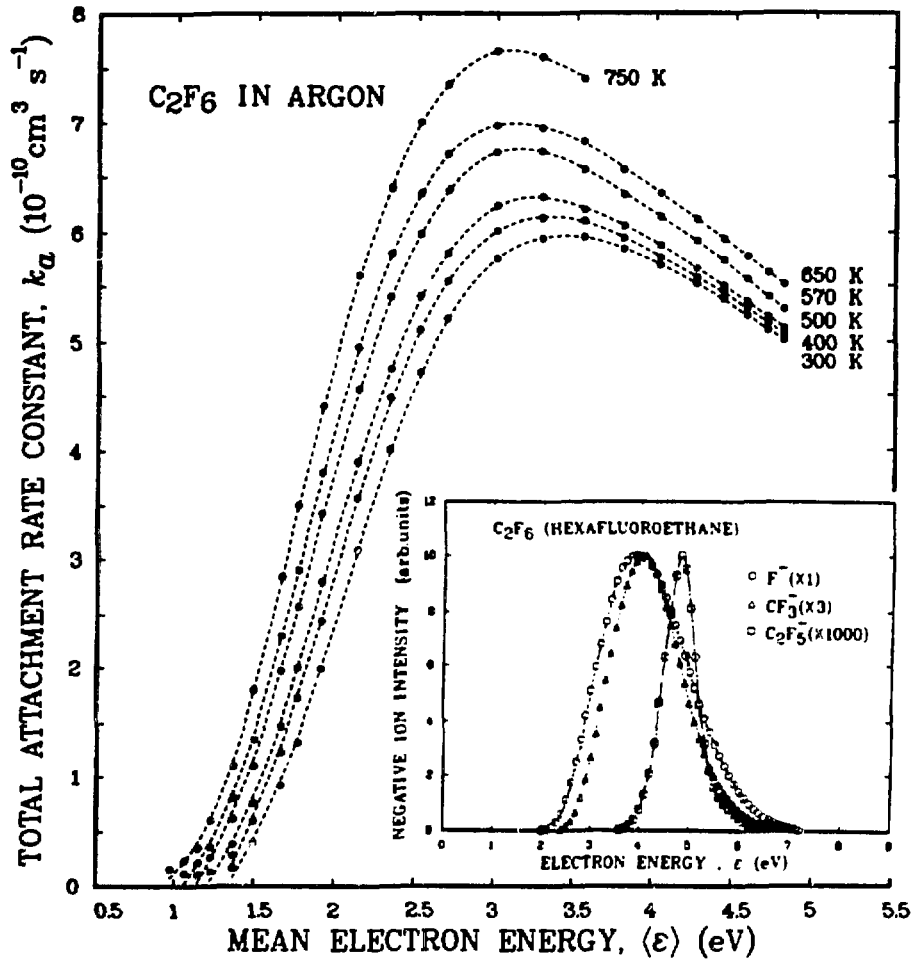


Figure 7. Total electron attachment rate constant as a function of mean electron energy for C₂F₆ in Ar buffer gas at various temperatures. The $k_a(\langle \epsilon \rangle, T)$ were independent of gas number density [15]. **Inset:**^a Relative intensity of the dissociative attachment fragment anions measured [17] in a low pressure beam study.

500 K. These measurements are shown in Fig. 9. The η/N_a data are consistent with those obtained in mixtures of C₂F₆ with Ar (Fig. 7).

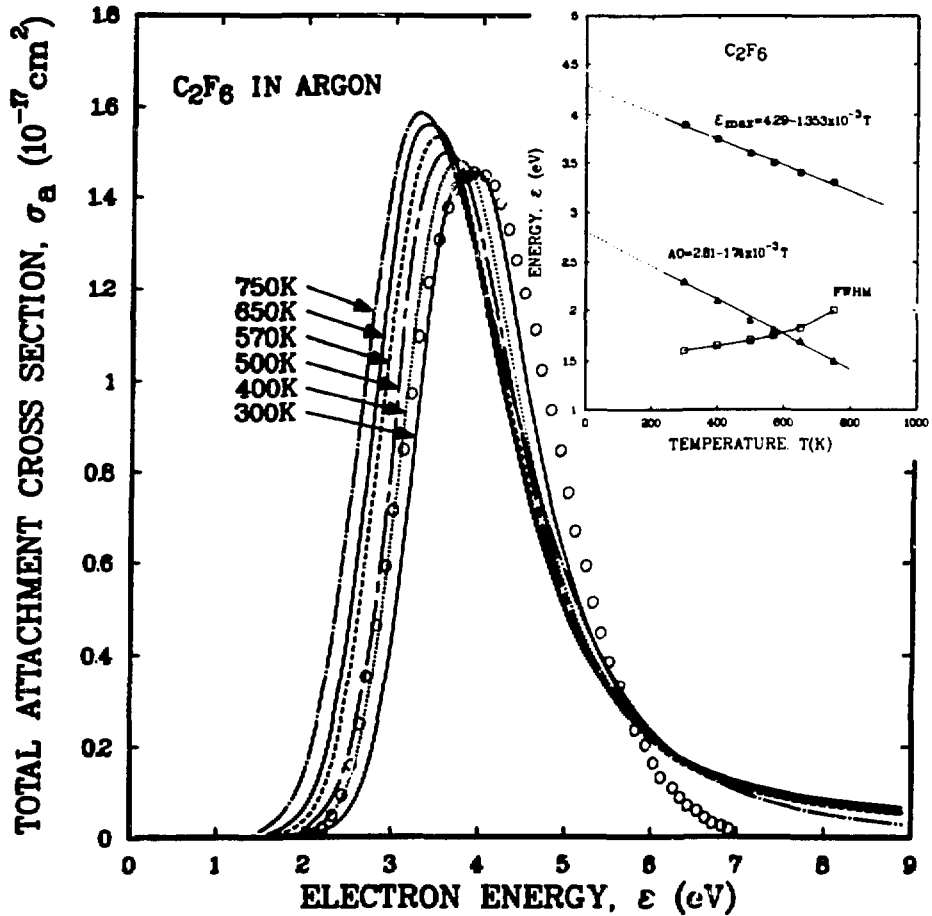


Figure 8. Total electron attachment cross section versus electron energy unfolded from the $k_a(\langle \epsilon \rangle, T)$ data in Fig. 7 at the indicated temperatures. The open circles (o) are the total electron beam cross section normalized to the peak of the swarm unfolded cross section for 300 K. **Inset:** Variation of the cross section peak position (ϵ_{\max}), cross section onset energy (AO), and cross section full width at half maximum (FWHM) with temperature (from Ref. 15).

Variation of the Energy Integrated Attachment Cross Section with Temperature and with the Molecule's Internal Energy

We have determined the energy integrated attachment cross section

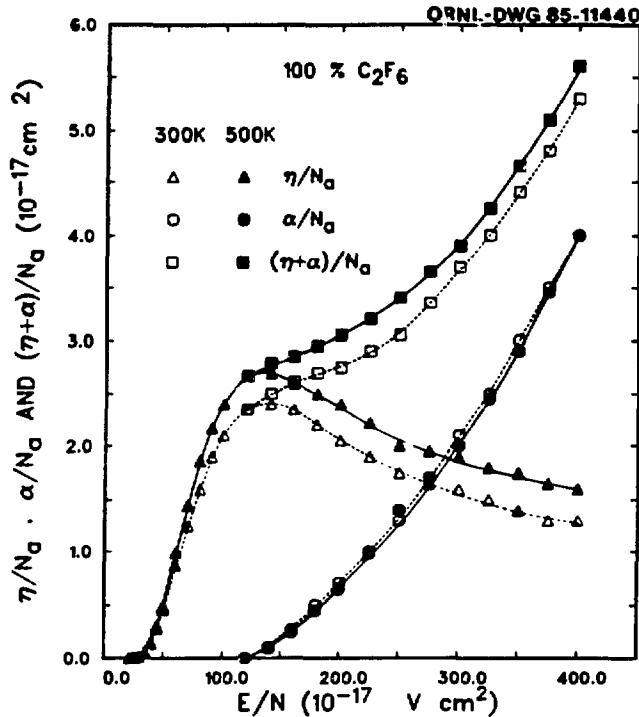


Figure 9. Electron attachment, η/N_a , and ionization, α/N_a , coefficients and their sum, $(\eta + \alpha)/N_a$, as a function of E/N at 300 and 500 K for pure C_2F_6 .

$$\int_{\epsilon_{\min}}^{\epsilon_{\max}} \sigma_{da}(\epsilon, T) d\epsilon \equiv \sigma_{EIA}(T) \quad (8)$$

from the respective $\sigma_{da}(\epsilon, T)$ measured for O^-/O_2 [18], Cl^-/HCl [11,19], $Cl^-/CClF_3$ [15], O^-/N_2O [7,20], SF_5^-/SF_6 [22,23], C_2F_6 [15] (all ions), and C_3F_8 [26] (all ions). These are plotted in Fig. 10a. The σ_{EIA} increases with T; this increase varies from molecule to molecule but not, however, in the simple fashion (i.e., the lower the σ_{EIA} at $T = 300$ K the faster its increase with T) stated earlier [27].

The fast increase of σ_{EIA} with T for SF_5^-/SF_6 and O^-/N_2O is most interesting. For SF_6 this may be due to the larger increase in p with increasing T probably because almost all 15 vibrational frequencies of SF_6 are small [774 cm^{-1} (singly degenerate); 642 cm^{-1} (doubly degenerate); 948, 616, 525, and 347 cm^{-1} (all triply degenerate)] [28] and hence high-lying levels of each mode are populated at relatively low T; also, it should be noted that the ϵ_{\max} for SF_5^-/SF_6 is low (~ 0.37 eV

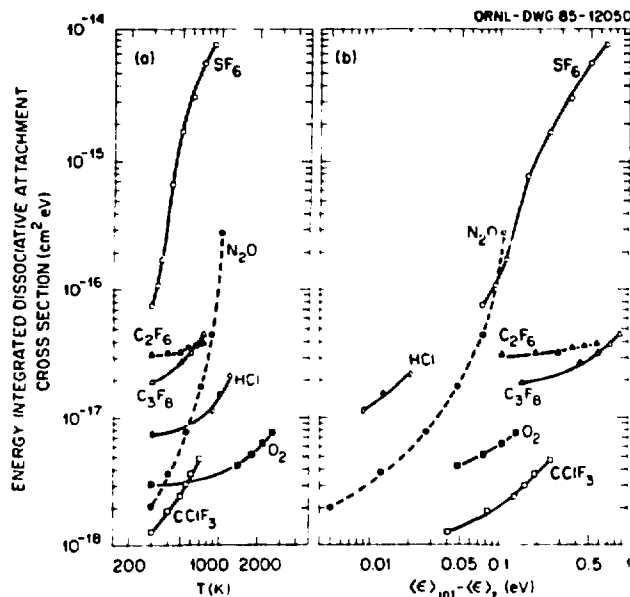


Figure 10. Energy integrated dissociative attachment cross section as a function of temperature (Fig. 10a) and excess internal energy $\langle \epsilon \rangle_{int} - \langle \epsilon \rangle_z$ (Fig. 10b) for O₂, HCl, N₂O, SF₆, CClF₃, C₂F₆, and C₃F₈ (see the text).

[24]) and that all six SF₅-F coordinates lead to SF₅⁻. For N₂O the large increase of σ_{EIA} with T may result from the fact that as T increases the hot N₂O* molecule (in the bending mode) [7,29] better facilitates upon electron collision the geometrical changes (from a straight N₂O* to a bend N₂O*) which are known to occur concomitantly with electron capture. It has been suggested [7] that the increased excitation in the bending mode of N₂O results in a lowering of the position of the NIS which leads to O⁻ formation; this would increase greatly the magnitude of σ_c and, thus, σ_{da} .

At any T there is a Boltzmann distribution B_v of the population of the vibrational levels v of each vibrational mode x. For a molecule with N normal modes, the vibrational energies of the normal mode x in the v = 0, 1, 2, ... levels (if we neglect anharmonicity) are $\epsilon_{v,x} = (v + \frac{1}{2})h\nu_x$ and for each x

$$B_v = e^{-\epsilon_{v,x}/kT} / \sum_{v=0}^{\infty} e^{-\epsilon_{v,x}/kT} \quad (9)$$

If we neglect the effect of rotational excitation and consider only the effect of vibrational excitation to be significant,

then for a diatomic molecule the cross section $\sigma_{da}(\epsilon, T)$ can be expressed as

$$\sigma_{da}(\epsilon, T) = \sum_{v=0}^{\infty} B_v \sigma_{da}^v(\epsilon, T) . \quad (10)$$

For a polyatomic molecule the summation in (10) must be carried out for all x . However, even if this were possible the x are not independent.

Let us then assume that as T increases each vibrational mode x of a polyatomic molecule is excited by an equal probability and that the total average internal energy $\langle \epsilon \rangle_{int}$ of the molecule is principally the sum of the energy in the various normal modes, x , viz.

$$\langle \epsilon \rangle_{int} = \sum_{x=1}^N \sum_{v=0}^{\infty} D_x B_x \epsilon_{v,x} , \quad (11)$$

where D_x is the degeneracy of the mode x . If we take $\langle \epsilon \rangle_{int}$ to be the molecule's total internal energy, then the molecule's excess energy would be $\langle \epsilon \rangle_{int} - \langle \epsilon \rangle_z$, where $\langle \epsilon \rangle_z$ ($\equiv \sum_{x=1}^N \frac{1}{2} h\nu_x$) is the zero-point energy. If now, $\langle \epsilon \rangle_{int} - \langle \epsilon \rangle_z$ is distributed quickly among the molecule's N vibrational degrees of freedom and can thus become available for the dissociative attachment reaction, one might expect a relationship between σ_{EIA} and $\langle \epsilon \rangle_{int} - \langle \epsilon \rangle_z$. Indeed, σ_{EIA} increases with $\langle \epsilon \rangle_{int} - \langle \epsilon \rangle_z$ (See Fig. 10b), although this increase differs--as expected--from one molecule to another. Actually, a better comparison might have been a plot of σ_{EIA} versus $(\langle \epsilon \rangle_{int} - \langle \epsilon \rangle_z) / \epsilon_{max}$. This would shift the C_2F_6 , C_3F_8 , O_2 , and $CClF_3$ curves to lower energies compared with SF_6 for which $\epsilon_{max} = 0.37$ eV. The fact that the curves in Fig. 10b for SF_6 and N_2O mesh reasonably well although ϵ_{max} for SF_6 is 0.37 eV and for N_2O it is 2.25 eV is consistent with the arguments presented earlier in this section that the ϵ_{max} for electron attachment to N_2O^* (bending mode) is lower than the ϵ_{max} for electron attachment to unexcited N_2O .

While further experimental and theoretical work is necessary (especially on polyatomic molecules) to fully understand the effect of temperature on $\sigma_{da}(\epsilon)$ and $\sigma_{EIA}(T)$, it is clear that for both diatomic and polyatomic molecules the changes in $k_{da}(\langle \epsilon \rangle)$, $\sigma_{da}(\epsilon)$, and $\sigma_{EIA}(T)$ with T result principally from an increase with T of the internal energy (\approx vibrational) of the molecule.

Effect of Temperature on Nondissociative Electron Attachment

The cross section, σ_{nd} , for nondissociative electron attachment--as that, σ_{da} , for dissociative varies profoundly with the gas temperature. Based on the data outlined in this section, this dependence arises from an effect of T on both σ_c and p' . However, while for dissociative attachment σ_{da} generally increases with T, for nondissociative attachment σ_{nd} generally decreases with T. Furthermore, while in dissociative attachment the increase in σ_{da} with T is predominantly due to a decrease in τ_a (and thus increase in p), the decrease in σ_{nd} for nondissociative attachment is due to a decrease in τ_a (and thus decrease in p) and σ_c . These conclusions are based on the following results.

SF₆

The cross section for the formation of SF₅⁻ from SF₆ at ~0.0 eV has been found to increase dramatically with increasing T (Fig. 10; Refs. 2, 22). However, a number of studies [2] have shown that the total attachment cross section or rate constant for SF₆ is independent of T to ~1200 K. This implies that the formation of SF₆⁻ (whose σ_{nd} peaks at ~0.0 eV [2]) decreases with increasing T. Direct evidence for this is provided by the early work of Hickam and Berg [30]. It is presently not possible to which quantity, σ_c or p' , to ascribe this decrease in σ_{nd} with T, although p' is expected to decrease with increasing T because τ_a is expected to decrease as the internal energy of SF₆^{-*} increases [2,6].

1-C₃F₆

A large decrease of the attachment rate constant for nondissociative electron attachment to perfluoropropylene (1-C₃F₆) with increasing T has been observed (Fig. 11; Refs. 2, 31, 32). This has been attributed [31,32] to a decrease in the τ_a of 1-C₃F₆^{-*} with increasing T.

C₆F₆

A profound decrease in the rate constant for electron attachment to perfluorobenzene (C₆F₆) with T has been reported for C₆F₆ (Fig. 12; Ref. 33). At T = 300 K, C₆F₆ forms parent C₆F₆⁻ ions by capturing near-zero energy electrons [2]; the τ_a of C₆F₆^{-*} was found to be ~10 μ s [2]. Spyrou and Christophorou [33] concluded that the decrease in $k_a(<\epsilon>)$ with T (Fig. 12) cannot be attributed to a decrease in τ_a (decrease in p) with T [the $k_a(<\epsilon>)$ did not depend on the gas number

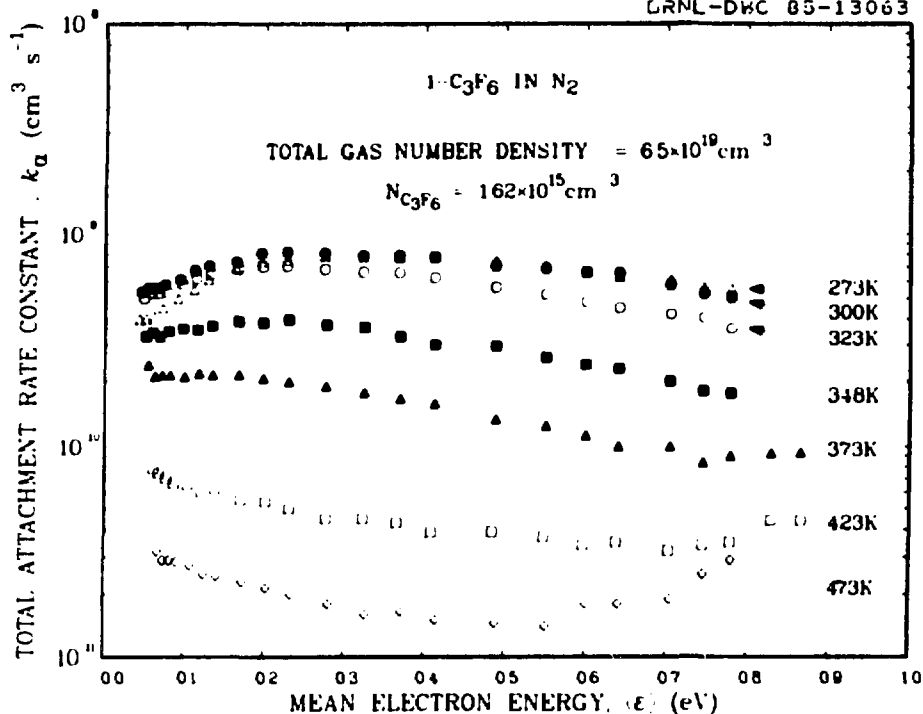


Figure 11. Total attachment rate constant versus mean electron energy for 1-C₃F₆ in N₂ at 273 ≤ T ≤ 473 K (from Ref. 32).

density at any T] or other by-products resulting from gas heating. They attributed it to a decrease in σ_c' and suggested that the increase in the internal energy of C₆F₆ affects rather profoundly the rate for the capture transition (i.e., to differences in the magnitude of σ_c' for the reactions $e + \text{C}_6\text{F}_6 \rightarrow \text{C}_6\text{F}_6^{-*}$ and $e + \text{C}_6\text{F}_6^* \rightarrow \text{C}_6\text{F}_6^{-*}$).

While much improvement in our understanding of the effects of the internal energy of a molecule on its electron attachment properties is still desirable, it is clear that as a rule σ_{da} increases and σ_{nd} decreases with increasing internal energy, that is, increasing T. It is also apparent that for both dissociative and nondissociative electron attachment p is the determining factor unless geometrical changes concomitant with electron capture effect changes in σ_c or σ_c' .

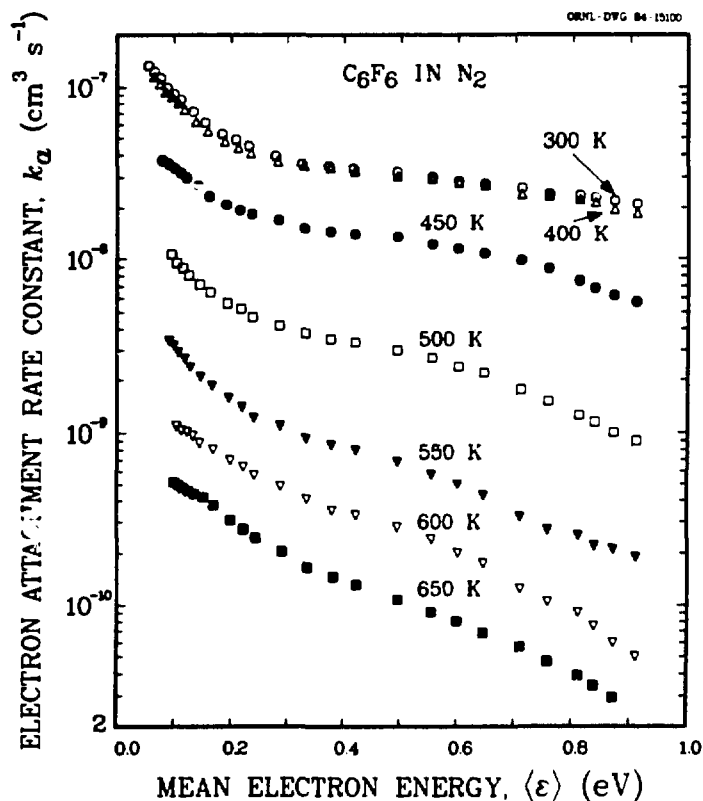


Figure 12. $k_a(\langle \epsilon \rangle, T)$ for C₆F₆ measured in a buffer gas of N₂. The C₆F₆ gas number density varied from 0.41 to 46.3 × 10¹³ cm⁻³ and that of N₂ from 2.25 to 6.44 × 10¹⁹ cm⁻³ (from Ref. 33).

Effect of Temperature on the Measured Attachment Rate Constant and Cross Section for Molecules for Which Both Dissociative and Nondissociative Electron Attachment Occur Over an Energy Range

Recently, we measured [26] the total electron attachment rate constant $k(\langle \epsilon \rangle)$ for C₃F₈ in Ar in the temperature range from 300 to 750 K. At $T \leq 425$ K the $k(\langle \epsilon \rangle)$ were found to increase with increasing total gas number density N_t over the entire $\langle \epsilon \rangle$ range (~ 0.5 to ~ 5 eV) covered in these experiments. At 450 K, the $k(\langle \epsilon \rangle)$ increased with N_t only for $\langle \epsilon \rangle \leq 1.2$ eV and at $T > 450$ K the $k(\langle \epsilon \rangle)$ were independent of N_t . The $k(\langle \epsilon \rangle)$ also showed a weak dependence on the attaching gas number density N_a due to the effect of the presence of the attaching gas on the distribution functions of pure Ar used in

the analysis; this effect was taken into account by measuring, for a fixed N_t , the $k_a(\langle\epsilon\rangle)$ as a function of N_a and extrapolating at each $\langle\epsilon\rangle$ the $k_a(N_a)$ to $N_a \rightarrow 0$.

In Fig. 13 are plotted the values, $k_1(\langle\epsilon\rangle)$, of $k_a(\langle\epsilon\rangle)$ for $N_a \rightarrow 0$ and $N_t \rightarrow \infty$ for all values of T that data were taken, and in Fig. 14 k_1 is plotted as a function of T for two values of $\langle\epsilon\rangle$. It is evident from these data that $k_1(\langle\epsilon\rangle)$ decreases to a minimum around 450 to 500 K and that it then increases as T increases.

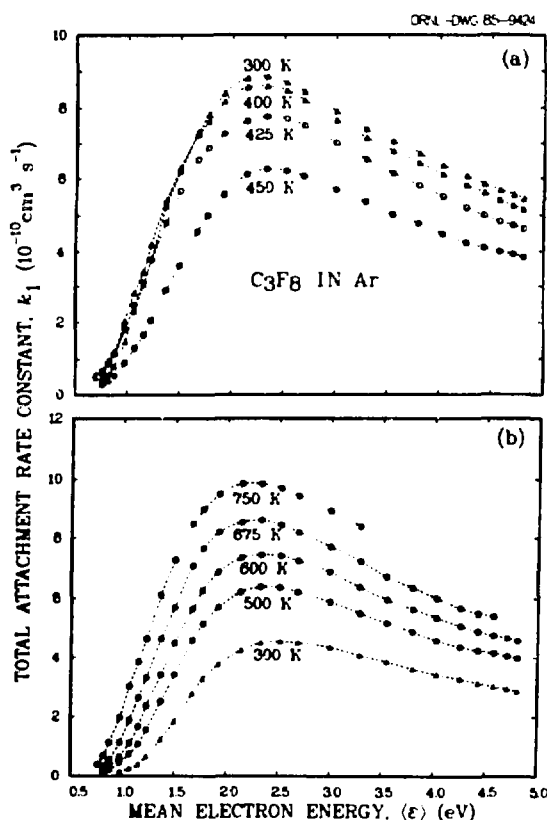


Figure 13. Electron attachment rate constant k_1 ($N_a \rightarrow 0$; $N_t \rightarrow \infty$) for C_3F_8 measured as a function of mean electron energy $\langle\epsilon\rangle$ in a buffer gas of Ar at (a) 300, 400, 425, and 450 K and (b) 500, 600, 675, and 750 K. The 300 K curve in Fig. 13b is the dissociative attachment contribution to the measured $k_a(\langle\epsilon\rangle)$ at this temperature (see the text and Ref. 26).

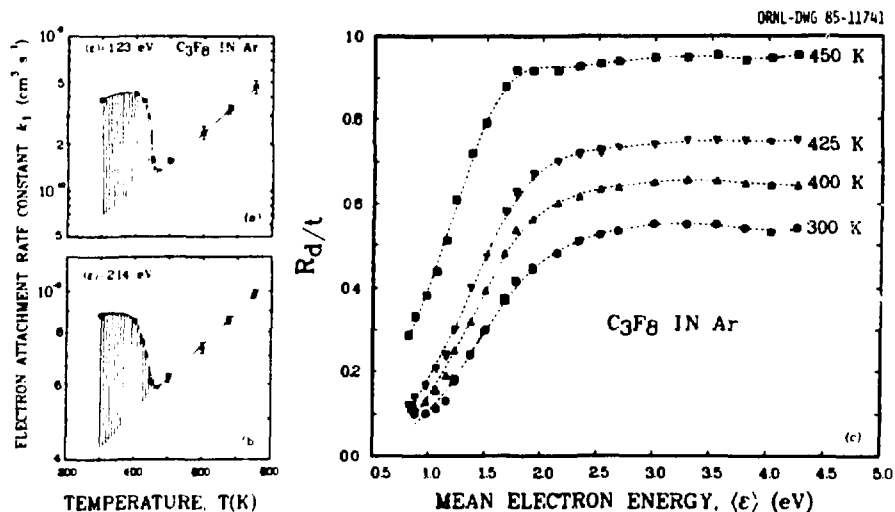


Figure 14. (a) and (b) Electron attachment rate constant k_1 ($N_a \rightarrow 0$; $N_t \rightarrow \infty$) for C_3F_8 versus temperature T at the mean electron energies $\langle \epsilon \rangle = 1.23$ and 2.14 eV. (c) Ratio R_d/t of the attachment rate constant due to dissociative attachment to the total attachment rate constant (see the text) versus the mean electron energy at 300, 400, 425, and 450 K obtained from extrapolation of the $k_a(\langle \epsilon \rangle)$ measured at $T \geq 500$ K to lower T (see the text).

The delicate dependence of $k_a(\langle \epsilon \rangle)$ on T can be understood by considering the results of electron beam and electron swarm studies. Single collision beam experiments on C_3F_8 indicated the presence of only dissociative attachment anions and established their identity and energy dependence; they also showed the existence of a number of NISS which lead to dissociative attachment [17]. On the other hand, the results of high pressure swarm experiments on C_3F_8 determined the magnitude of the total attachment rate constant and cross section as a function of electron energy and their total pressure dependence [26,34]; they indicated that in addition to the NISS which lead to dissociative attachment (observed in single collision beam experiments) there exists another, lower-lying NIS which is attractive and which leads to the formation of parent negative ions with $\tau_a < 10^{-6}$ s [26,34]. These findings and the observed effects of T on $k_a(\langle \epsilon \rangle)$ (Figs. 13 and 14) and $\sigma_{da}(\epsilon)$ (Fig. 15) have been ascribed to electron attachment via an attractive NIS (with a positive electron affinity and a steep repulsive part) leading to parent anions and to one (or more) repulsive NISS leading to fragment anions.

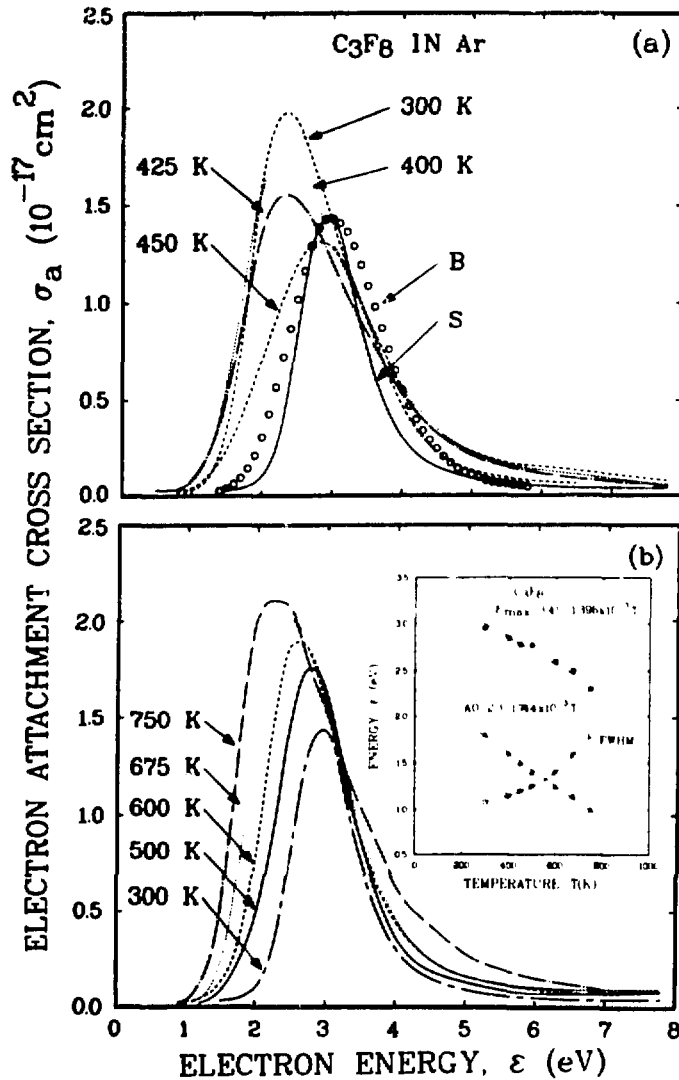


Figure 15. Swarm unfolded total electron attachment cross section $\sigma_a(\epsilon)$ for C_3F_8 obtained [26] from the $k_1(\langle\epsilon\rangle)$ in Ar shown in Fig. 13 at (a) 300, 400, 425, and 450 K and (b) 300, 500, 600, 675, and 750 K. In Fig. 15a is plotted also the dissociative attachment cross section $\sigma_{da}(\epsilon)$ obtained from the swarm data at 300 K (curve S) and the dissociative cross section measured in an electron beam experiment (curve B) which has been normalized to the peak of $\sigma_a(\epsilon)$ (see the text). In Fig. 15b the curve for 300 K is the curve S of Fig. 15a. Inset: Variation of peak energy (ϵ_{max}), appearance onset (AO), and full width at half maximum (FWHM) of the total dissociative attachment cross section of C_3F_8 with temperature.

The delicate dependence of $k_a(\langle \epsilon \rangle)$ on T (Figs. 13 and 14) can thus be considered as the result of two opposite effects of T : one on the rate constant for nondissociative and the other on the rate constant for dissociative electron attachment. As it has been shown in the previous section, as a rule, the rate constant for pure nondissociative attachment processes decreases and that for pure dissociative attachment processes increases with increasing T . At each $\langle \epsilon \rangle$, the magnitude of k_a is determined by the relative magnitudes of the rate constants for nondissociative and dissociative electron attachment both of which depend on T . From the data in Fig. 14, it is apparent that for $T \gtrsim 500$ K the principal contribution to the measured k_a originates from dissociative attachment; this is supported by the lack of any dependence of k_a on N_0 at high T and from the observed increases in k_a with T^a (500 to 750 K) which are characteristic of molecules^a which attach electrons dissociatively. We then assumed [26] that for $T \gtrsim 500$ K the measured k_a is due entirely to dissociative attachment and extrapolated^a (at various values of $\langle \epsilon \rangle$) the measured k_a at $T \gtrsim 500$ K to lower T (see Figs. 14a,b) in an effort to estimate the dissociative attachment contribution to the measured k_a at $T < 500$ K, where nondissociative attachment takes place and becomes progressively more significant with decreasing T . From plots such as those in Figs. 14a,b we estimated [26] the ratio $R_{d/t}(\langle \epsilon \rangle)$ of the dissociative to the total attachment rate constant as a function of $\langle \epsilon \rangle$ for 300, 400, 425, and 450 K. These estimates are given in Fig. 14c and show that the contribution of dissociative attachment processes to the measured rate constant is both a function of $\langle \epsilon \rangle$ and T .

The total electron attachment rate constants $k_1(\langle \epsilon \rangle)$ (Fig. 13) were unfolded [26] and the total attachment cross sections $\sigma(\epsilon, T)$ obtained are shown in Fig. 15. They decrease in magnitude^a with increasing T from 300 to ~ 450 K (Fig. 15a) because in this T range the total cross section contains a large contribution (which decreases as T increases) from nondissociative attachment. An increase in T beyond ~ 450 K (Fig. 15b) results in an overall increase in the magnitude and full width at half maximum--and a shift to lower energy of the onset and energy of the peak (see inset of Fig. 15b)--resulting from the increasingly larger contribution of the dissociative attachment component to the total cross section.

In Fig. 15a are also compared the cross sections due to only the dissociative attachment contribution to the total cross section at 300 K (curve S) and the total (for all fragment anions) dissociative attachment cross section for C_3F_8 measured in a single collision electron beam study [17];

the latter was normalized to the peak value of the former. It is seen that the peak positions of the two cross section functions agree well and that both lie at a higher energy than the total unfolded cross section $\sigma_a(\epsilon, 300 \text{ K})$.

Conclusions

While much improvement in our understanding of the effects of internal energy of a molecule on its electron attaching properties is still desirable, it is clear that as a rule σ_{da} increases and σ_{nd} decreases with increasing T. It is also apparent from the data obtained to date that for both dissociative and nondissociative electron attachment the survival probability is the determining factor (shortening of τ_s in dissociative and shortening of τ_a in nondissociative electron attachment with increasing T) unless geometrical changes concomitant with electron capture effect changes in $\sigma_c(\sigma'_c)$.

From the practical point of view, both the increases and the decreases in $k(\langle\epsilon\rangle)$ with T are significant because they affect the conductivity/dielectric strength properties of the gaseous medium. The sensitivity of $k(\langle\epsilon\rangle)$ to changes in T requires that proper attention be given to the operating temperature range of a given device. Interestingly, the sensitivity of $k(\langle\epsilon\rangle)$ to T (e.g., C_6F_6 ; see Fig. 12) can perhaps be employed to change the conducting/insulating properties of a gaseous medium by varying T.

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